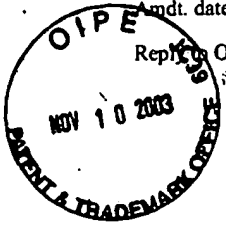


PATENT

Appl. No. 10/077,072

Amdt. dated 11/7/2003

Reply to Office action of 09/09/2003



IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the application of:

FISCHER et al.

Application No: 10/077,072

Filed: February 14, 2002

For: A PLASMA PROCESSING APPARATUS  
AND METHOD FOR CONFINING AN RF  
PLASMA UNDER VERY HIGH GAS FLOW  
AND RF POWER DENSITY CONDITIONS

Group Art Unit: 2821

Examiner: LEE, Wilson

Atty. Docket No: P0877

Date: November 7, 2003

CERTIFICATE OF MAILING

I hereby certify that this correspondence is being deposited with the United States Postal Service as First Class Mail in an envelope addressed to: Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450 on November 7, 2003.

Signed: Sharon Tillery

Sharon Tillery

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

AMENDMENT

Dear Sir:

In response to the Office Action mailed on September 9, 2003, please enter the following amendments and remarks in the above-identified patent application:

Amendments to the specifications begin on page 2.

Amendments to the claims are reflected in the listing of claims, which begins on page 3 of this paper.

Remarks/Arguments begin on page 8 of this paper.

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Approved  
to be entered  
WS 1-20-04